# *Call for papers*

# IC-PLANTS 2013

## *The 6th International Conference on Plasma-Nanotechnology & Science*

February 2-3, 2013

**Gero Synergy Center, Gero-city, Gifu, JAPAN**

**Sponsored by -** Plasma Nanotechnology Research Center (PLANT), Nagoya University
**Co-sponsored by -** Japan Society for the Promotion of Science,
(tentative) - Aichi Science & Technology Foundation
- Scientific Research on Innovative Areas
"Frontier science of interactions between plasmas and nano-interfaces"
**Supported by -** Tokai division of the Japan Society of Applied Physics
(tentative) - Tokai Branch of the Institute of Electrical Engineers of Japan
- Plasma Electronics Division, Japan Society of Applied Physics
- Nagoya Urban Industrial Promotion Corporation
- Research Center for Sustainable Energy and Technology, Kanazawa University

Plasma processing technologies are the state of the art technologies leading the way through ultra-high performances in Nano-materials, microelectronic devices, flat panels, etc. IC-PLANTS is organized to offer opportunities for discussions and exchange of recent progresses of Plasma Science and Nanotechnology among the Plasma CoEs in the world. It is absolutely necessary to collaborate between the research communities for clearing the complex issues in the interdisciplinary research fields. The 6th IC-PLANTS is to be held in Gero Synergy Center ‘ACTIVE’, Gero-city, Japan. The organizing committee invites you to the conference and welcomes the submission of your papers.

## General Topics

**Theme:** Fundamentals of plasma processes
Plasma technology and MEMS
Atmospheric pressure plasma and Plasma biotechnology
Interactions between plasmas and nano-interfaces

**Topics:** Nano-fabrication / Diagnostics and monitoring of plasmas and Reaction surfaces / Nano-electronics / Nano-biology / Interdisciplinary or integrated research with Plasma technologies / Nano-optics / MEMS& NEMS technologies / Process technologies for flat panel display / Environmental technologies / Equipment technologies / Emerging new concept

## Submission of Abstracts (Oral and Poster Sessions)

Abstract (A4 size, up to two pages) should be submitted by **October 31, 2012** via the web.
Template is available at http://www.plasma.engg.nagoya-u.ac.jp/IC-2013/.

## Registration Fee

**Early (by November 30, 2012) : General : 10,000JPY, Student : 1,000JPY**
**On-site : General : 15,000JPY, Student : 2,000JPY**

## Organizing Committee Chair

***Chair, Noriyasu Ohno,*** Professor, Department of Energy Engineering and Science, Nagoya University
***Co-Chair, Masaharu Shiratani,*** Director, Center of Plasma Nano-interface Engineering, Kyushu University

## Contact

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